

85. An optical system for detecting anomalies of a sample, comprising:
optics directing a beam of radiation along a first path at an oblique angle of incidence onto a surface of the sample;

at least two detectors comprising a first detector located to detect light scattered by the surface within a first range of collection angles from a normal direction to the surface and a second detector comprising a curved mirrored surface and located to detect light scattered by the surface within a second range of collection angles from the normal direction, said second range being different from the first range; and

a device comparing outputs of the two detectors to distinguish between a particle and a COP on the surface.

86. The system of claim 85, wherein the collection angles of said first range are smaller than the collection angles of said second range, said first detector including at least one lens for collecting light to be detected.

87. The system of claim 85, said mirrored surface being substantially ellipsoidal in shape.

88. A method for detecting anomalies of a sample, comprising:
directing a beam of radiation along a first path at an oblique angle of incidence onto a surface of the sample;

detecting light scattered by the surface within a first and a second range of collection angles from a normal direction to the surface, said second range being different from the first range, wherein light within the first range is detected by means of a first detector and light within the second range is collected by a curved mirrored surface and detected by means of a second detector; and

comparing outputs of the two detectors to distinguish between a particle and a COP on the surface.

85. An optical system for detecting anomalies of a sample, comprising:

~~means for optics~~ directing a beam of radiation along a first path at an oblique angle of incidence onto a surface of the sample;

~~detecting means including at least two detectors, said at~~ least two detectors comprising a first detector located to detect light scattered by the surface within a first range of collection angles from a normal direction to the surface and a second detector comprising a curved mirrored surface and located to detect light scattered by the surface within a second range of collection angles from the normal direction, said second range being different from the first range; and

a device ~~means for~~ comparing outputs of the two detectors to distinguish between a particle and a COP on the surface.

86. The system of claim 85, wherein the collection angles of said first range are smaller than the collection angles of said second range, said first detector including at least one lens for collecting light to be detected, ~~said second detector including a mirrored surface for receiving scattered radiation from the sample surface.~~

87. The system of claim ~~86~~85, said mirrored surface being substantially ellipsoidal in shape.

88. A method for detecting anomalies of a sample, comprising:

directing a beam of radiation along a first path at an oblique angle of incidence onto a surface of the sample;

detecting light scattered by the surface within a first and a second range of collection angles from a normal direction to the surface, said second range being different from the first range, wherein light within the first range is detected by means of a first detector and light within the second range is collected by a curved mirrored surface and detected by means of a second detector; and

comparing outputs of the two detectors to distinguish between a particle and a COP on the surface.